

## ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of  
Invention

SYSTEMS FOR INSPECTING WAFERS AND RETICLES  
WITH INCREASED RESOLUTION

Application Number: 10/725744



Confirmation Number: 3066

First Named Applicant: Steven Lange

Attorney Docket Number: 5589-05201

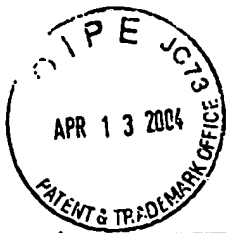
Search string: ( 5825043 or 6191429 or 5298939 or 4346164  
or 6493156 or 5610683 or 5040020 or 4898804  
or 4544626 or 4509852 or 5023424 or 5900354  
or 5004307 or 5121256 ).pn.

### US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5825043	1998-10-20	Suwa			
	2	6191429	2001-02-20	Suwa			
	3	5298939	1994-03-29	Swanson et al.			
	4	4346164	1982-08-24	Tabarelli et al.			
	5	6493156	2002-12-10	Oh et al.			
	6	5610683	1997-03-11	Takahashi			
	7	5040020	1991-08-13	Rauschenbach et al.			
	8	4898804	1990-02-06	Rauschenbach et al.			
	9	4544626	1985-10-01	Sullivan			
	10	4509852	1985-04-09	Tabarelli et al.			
	11	5023424	1991-06-11	Vaught			
	12	5900354	1999-05-04	Batchelder			
	13	5004307	1991-04-02	Kino et al.			
	14	5121256	1992-06-09	Corle et al.			

Signature



Examiner Name	Date
Michael Statler	10-14-05

